CRL 726

RF MEMS Design and Technology

1st Semester **2006 Major**

Date: 01.12.2006 **Venue: II 332** **Time: 10.30 – 12.30 am**

Marks: 40 **Marks distribution**

1. Draw the process flow of two port (vertical displacement) MEMS resonator.	10.0
2. What are the limiting factors for high frequency of a cantilever MEMS?	5.0
3. What are the MEM switch specifications?	5.0
4. What are the MEM resonator specifications?	5.0
5. Draw the electrical equivalent of two port vertical displacement microresonator.	5.0
6. Write in short the MEMS miniaturization motivations.	5.0
7. What are the wafer bonding considerations (in short)?	5.0